

Attorney Docket No. 09792909-5787

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)	Group Art Unit:
)	
Fumikatsu UESAWA)	Examiner:
)	
Application No.)	
)	
Filed:)	
)	
For: Method of Manufacturing a)	
Semiconductor Apparatus with)	
Tapered Aperture Pattern to Form a)	
Predetermined Line Width)	

Mail Stop Patent Application
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT PURSUANT TO 1.53(b)

Dear Sir:

Prior to substantively examining the instant application, please enter the following amendments.